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PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Masahiro FURUSAWA et al.

Application No.: 10/026,635

Filed: December 27, 2001

Docket No.: 111589

For: METHOD FOR MAKING THIN FILM AND ELECTRONIC APPARATUS

SUPPLEMENTAL PRELIMINARY AMENDMENT

Director of the U.S. Patent and Trademark Office
Washington, D. C. 20231

Sir:

Prior to initial examination, please amend the above-identified application as follows:

IN THE ABSTRACT:

Please replace the Abstract filed with the Substitute Abstract attached hereto.

IN THE SPECIFICATION:

Please replace the specification with the Substitute Specification attached hereto.

IN THE CLAIMS:

Please replace claims 1-9 as follows:

1. (Amended) A method for forming a thin film by chemical vapor deposition,
comprising the steps of:

placing a liquid containing a raw material for the thin film over one of a part
and a plurality of parts of a substrate; and